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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor: CHYH-YIH CHANG, ET AL.)
Application Serial No.: 10/702,437) Attorney Docket No.: IT0118-US
Filed: November 7, 2003)
Title: SUBSTRATE-BIASED SILICON DIODE)
FOR ELECTROSTATIC DISCHARGE)
PROTECTION AND FABRICATION)
METHOD)

SUBMISSION OF REVOCATION OF POWER OF ATTORNEY
AND GRANT OF POWER OF ATTORNEY

Assistant Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicants hereby submit the attached Revocation of Power of Attorney and Grant of Power of Attorney in the above-identified application. Should there be any questions with respect to this submission a representative of the Patent Office is requested to contact the undersigned.

Respectfully submitted,

CHYH-YIH CHANG, ET AL.

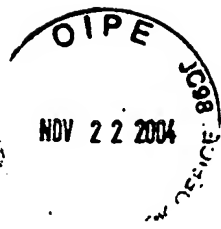
Date: November 22, 2004

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Customer No. 28970



PATENT
Customer No. 28970

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Patent Application and Patent Numbers: See attached "Schedule A"

REVOCATION OF POWER OF ATTORNEY
AND GRANT OF NEW POWER OF ATTORNEY

The undersigned, a representative authorized to sign on behalf of the assignee owning all of the interest in the listed and pending patent applications and issued patents on the attached sheet (Schedule A), hereby revokes all previous powers of attorney or authorization of agent granted in these patents before the date of execution hereof. The undersigned verifies that **INDUSTRIAL TECHNOLOGY RESEARCH INSTITUTE** is the assignee of the entire right, title, and interest in each of the pending patent applications and issued patents listed on the attached Schedule A and is identified as the assignee by assignments from the inventor(s) in the listed pending patent applications and issued patents as filed accordingly at the U.S. Patent and Trademark Office. The undersigned certifies that the evidentiary documents have been reviewed and to the best of the undersigned's knowledge and belief, title in each of the pending patent applications and issued patents listed on the attached Schedule A is in the assignee **INDUSTRIAL TECHNOLOGY RESEARCH INSTITUTE**.



By the undersigned's signature, **INDUSTRIAL TECHNOLOGY RESEARCH INSTITUTE** hereby grants power of attorney for each of the pending patent applications and issued patents listed on the attached Schedule A to **SHAW PITTMAN LLP**, Michael D. Bednarek, Reg. No. 32,329; Lawrence J. Gotts, Reg. No. 31,163; Aslan Baghdadi, Reg. No. 34,542; Yitai Hu, Reg. No. 40,653; Elizabeth M. Roesel, Reg. No. 34,878; David C. Isaacson, Reg. No. 38,500; Steven P. Arnheim, Reg. No. 43, 475; Poh C. Chua, Reg. No. 44,615; Michael A. Oblon, Reg. No. 42,956; Lawrence D. Eisen, Reg. No. 41,009; Mark Koehn, Reg. No. 46,271; Michelle S. Marks, Reg. No. 41,971; Brett C. Martin, Reg. No. 52,000; Chad D. Wells, Reg. No. 50,875; Tara L. Hutchings, Reg. No. 46,559; John Kasha, Reg. No. 53,100; Ann P. McGeehan, Reg. No. 45,839; June E. Cohan, Reg. No. 43,741; and Joanne Kim, Reg. No. 51,193, both jointly and separately as its attorneys with full power of substitution and revocation, to transact all business in the Patent and Trademark Office connected with each of the pending patent applications and issued patents listed on the attached Schedule A.

Please send all future correspondence concerning the pending patent applications and issued patents listed on the attached Schedule A to SHAW PITTMAN LLP at the following address:

Shaw Pittman LLP
1650 Tysons Blvd.
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Dated: Sept. 9, 2004

By: Benjamin Wang
(name) Benjamin Wang
(title) Deputy General Director
Industrial Technology Research Institute

**SCHEDULE A**

SERIAL NUMBER	FILING DATE	TITLE	PATENT NUMBER	ISSUED DATE
09/749,377	Dec. 28, 2000	Substrate-Biased Silicon Diode for Electrostatic Discharge Protection and Fabrication Method	6,690,065	Feb. 10, 2004
10/092,254	March 7, 2002	Substrate-Biased Silicon Diode for Electrostatic Discharge Protection and Fabrication Method	6,611,026	Aug. 26, 2003
10/702,437	Nov. 7, 2003	Substrate-Biased Silicon Diode for Electrostatic Discharge Protection and Fabrication Method	N/A	N/A
10/218,456	Aug. 15, 2002	Method and System of Interference Cancellation in Multi-Cell CDMA Systems	N/A	N/A

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